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	Application No.	Applicant(s)		
Notice of Allowability	10/661,702	HASHIMOTO, SHIN-ICHI		
	Examiner	Art Unit		
	Kiet T. Nguyen	2881		
The MAILING DATE of this communication appears on the cover sheet with the correspondence address All claims being allowable, PROSECUTION ON THE MERITS IS (OR REMAINS) CLOSED in this application. If not included herewith (or previously mailed), a Notice of Allowance (PTOL-85) or other appropriate communication will be mailed in due course. THIS NOTICE OF ALLOWABILITY IS NOT A GRANT OF PATENT RIGHTS. This application is subject to withdrawal from issue at the initiative of the Office or upon petition by the applicant. See 37 CFR 1.313 and MPEP 1308.				
 This communication is responsive to The allowed claim(s) is/are <u>1-9</u>. The drawings filed on <u>12 September 2003</u> are accepted by Acknowledgment is made of a claim for foreign priority ur All b) Some* c) None of the: 	nder 35 U.S.C. § 119(a)-(d) or (f).			
1. 🖂 Certified copies of the priority documents have been received.				
2. Certified copies of the priority documents have been received in Application No				
 Copies of the certified copies of the priority documents have been received in this national stage application from the International Bureau (PCT Rule 17.2(a)). 				
* Certified copies not received:				
5. Acknowledgment is made of a claim for domestic priority under 35 U.S.C. § 119(e) (to a provisional application) since a specific reference was included in the first sentence of the specification or in an Application Data Sheet. 37 CFR 1.78.				
(a) \square The translation of the foreign language provisional application has been received.				
6. Acknowledgment is made of a claim for domestic priority under 35 U.S.C. §§ 120 and/or 121 since a specific reference was included in the first sentence of the specification or in an Application Data Sheet. 37 CFR 1.78.				
Applicant has THREE MONTHS FROM THE "MAILING DATE" of this communication to file a reply complying with the requirements noted below. Failure to timely comply will result in ABANDONMENT of this application. THIS THREE-MONTH PERIOD IS NOT EXTENDABLE.				
7. A SUBSTITUTE OATH OR DECLARATION must be submitted. Note the attached EXAMINER'S AMENDMENT or NOTICE OF INFORMAL PATENT APPLICATION (PTO-152) which gives reason(s) why the oath or declaration is deficient.				
8. CORRECTED DRAWINGS (as "replacement sheets") must be submitted. (a) including changes required by the Notice of Draftsperson's Patent Drawing Review (PTO-948) attached 1) hereto or 2) to Paper No				
(b) ☐ including changes required by the proposed drawing correction filed, which has been approved by the Examiner.				
(c) ☐ including changes required by the attached Examiner's Amendment / Comment or in the Office action of Paper No				
Identifying indicia such as the application number (see 37 CFR 1.84(c)) should be written on the drawings in the front (not the back) of each sheet. Replacement sheet(s) should be labeled as such in the margin according to 37 CFR 1.121(d).				
9. DEPOSIT OF and/or INFORMATION about the deposit of BIOLOGICAL MATERIAL must be submitted. Note the attached Examiner's comment regarding REQUIREMENT FOR THE DEPOSIT OF BIOLOGICAL MATERIAL.				
Attachment(s)				
1⊠ Notice of References Cited (PTO-892)	5∏ Notice of Informal Pa	atent Application (PTO	-152)	
 2 Notice of Draftperson's Patent Drawing Review (PTO-948) 3 Information Disclosure Statements (PTO-1449 or PTO/SB/08 Paper No. 20040425 		6 Interview Summary (PTO-413), Paper No		
	^{3),} 7☐ Examiner's Amendm	ent/Comment		
4 Examiner's Comment Regarding Requirement for Deposit	8⊠ Examiner's Stateme	nt of Reasons for Allov	vance	
of Biological Material	9∐ Other .	Tuy		
		KIET T. NGUYEN IMARY EXAMINER		

Application/Control Number: 10/661,702

Art Unit: 2881

The following is an examiner's statement of reasons for allowance:

The prior art fails to disclose an electron beam exposure apparatus having a deflection amount correction section for computing a position of a wafer stage at exposure time based on moving speed between a first time point and a second time point of the wafer stage measured by a stage speed computing section, and for controlling deflection amount of an electron beam at the exposure time as recited in claims 1, 8 and 9.

Any comments considered necessary by applicant must be submitted no later than the payment of the issue fee and, to avoid processing delays, should preferably accompany the issue fee. Such submissions should be clearly labeled "Comments on Statement of Reasons for Allowance."

Any inquiry concerning this communication or earlier communications from the examiner should be directed to Kiet T. Nguyen whose telephone number is 571-272-2479. The examiner can normally be reached on Monday-Friday from 8.00 AM to 6.00 PM.

If attempts to reach the examiner by telephone are unsuccessful, the examiner's supervisor, John R Lee, can be reached on Monday-Friday. The fax phone number for the organization where this application or proceeding is assigned is 703-872-9306.

Information regarding the status of an application may be obtained from the Patent Application Information Retrieval (PAIR) system. Status information for published applications may be obtained from either Private PAIR or Public PAIR.

Status information for unpublished applications is available through Private PAIR only.

Application/Control Number: 10/661,702

Art Unit: 2881

For more information about the PAIR system, see http://pair-direct.uspto.gov. Should you have questions on access to the Private PAIR system, contact the Electronic Business Center (EBC) at 866-217-9197 (toll-free).

KIET T. NGUYEN PRIMARY EXAMINER

Page 3